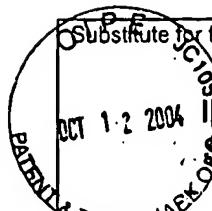


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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet	1	of	4	Attorney Docket Number	14434.4001
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U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No. ¹	U.S. Patent Document Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
✓.R.	AA	US 2004/0070772 A1	04-15-2004	Shchegrov et al.
✓.R.	AB	US 2004/0017574 A1	01-29-2004	Vuong et al.
✓.R.	AC	US 2003/0206298 A1	11-06-2003	Bischoff et al.
✓.R.	AD	US 2002/0101585 A1	08-01-2002	Benesch et al.
✓.R.	AE	US 2002/0051564 A1	05-02-2002	Benesch et al.
✓.R.	AF	US 6,721,052 B2	04-13-2004	Zhao et al.
✓.R.	AG	US 6,704,661 B1	03-09-2004	Opsal et al.
✓.R.	AH	US 6,694,284 B1	02-17-2004	Nikoonaahad et al.
✓.R.	AI	US 6,694,275 B1	02-17-2004	Jakadar et al.
✓.R.	AJ	US 6,689,519 B2	02-10-2004	Brown et al.

FOREIGN PATENT DOCUMENTS				
Examiner Initials	Cite No. ¹	Foreign Patent Document Country ³ Number ⁴ Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
	BA			
	BB			

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS				
Examiner Initials'	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
✓.R.	CA	LOGOFATU, PETRE C., "UV Scatterometry," Proceedings of SPIE: Metrology, Inspection, and Process Control for Microlithography XVII, May 2003, pp. 208-214, Vol. 5038, The International Society for Optical Engineering (SPIE), Bellingham, Washington, USA.		T ²
✓.R.	CB	HETTWER, ANDREA et al., "Phi-Scatterometry for Integrated Linewidth and Process Control in DRAM Manufacturing," IEEE Transactions on Semiconductor Manufacturing, November 2002, pp. 470-477, Vol. 15, No. 4, Institute of Electrical and Electronics Engineers (IEEE), New York, New York, USA.		

Examiner Signature		Date Considered	1 Nov 2004
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹Applicants unique citation designation number (optional). ²See Kinds of U.S. Patent Documents at www.uspto.gov or MPEP 901.04. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

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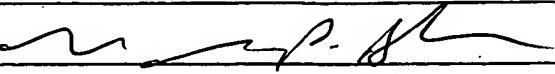
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Substitute for form 1449A/PTO				Complete if Known	
				Application Number	10/718,780
				Filing Date	November 20, 2003
				First Named Inventor	Mehrdad NIKOONAHAD
				Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
(use as many sheets as necessary)				Attorney Docket Number	
Sheet	2	of	4	14434.4001	

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No. ¹	U.S. Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number-Kind Code ² (if known)		
N.A.	DA	US 6,665,071 B2	12-16-2003	Hovinen et al.
N.A.	DB	US 6,645,824 B1	11-11-2003	Yang et al.
N.G.	DC	US 6,636,843 B2	10-21-2003	Doddi et al.
N.D.	DD	US 6,633,831 B2	10-14-2003	Nikoonahad et al.
N.B.	DE	US 6,608,690 B2	08-19-2003	Niu et al.
N.B.	DF	US 6,608,686 B1	08-19-2003	Lane et al.
N.L.	DG	US 6,583,731 B2	06-24-2003	Chan et al.
J.B.	DH	US 6,483,580 B1	11-19-2002	Xu et al.
N.R.	DI	US 6,451,621 B1	09-17-2002	Rangarajan et al.
N.H.	DJ	US 6,433,878 B1	08-13-2002	Niu et al.

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Examiner Initials	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
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	EA			
	EB			

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS				
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J.D.	FA	NIU, XINHUI et al., "Specular Spectroscopic Scatterometry," IEEE Transactions on Semiconductor Manufacturing, May 2001, pp. 97-111; Vol. 14, No. 2; Institute of Electrical and Electronics Engineers (IEEE), New York, New York, USA.		
N.B.	FB	SCHNEIDER, CLAUS et al., "Integrated metrology: An enabler for advanced process control (APC)," Proceedings of SPIE: In-Line Characterization, Yield, Reliability, and Failure Analysis in Microelectronic Manufacturing II, April 2001, pp. 118-130, Vol. 4406, The International Society for Optical Engineering (SPIE), Bellingham, Washington, USA.		

Examiner Signature		Date Considered	1 Nov 2004
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				First Named Inventor	Mehrdad NIKOONAHAD
				Art Unit	Not Yet Assigned
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Sheet	3	of	4	Attorney Docket Number	14434.4001

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		Number-Kind Code ² (if known)		
W-A	GA	US 6,429,943 B1	08-06-2002	Opsal et al.
N-R	GB	US 6,323,946 B1	11-27-2002	Norton
N-H	GC	6,124,924	09-26-2000	Feldman et al.
N-B	GD	5,771,094	06-23-1998	Carter et al.
N-B	GE	5,747,813	05-05-1998	Norton et al.
N-R	GF	5,608,526	03-04-1997	Piwonka-Corle et al.
N-B	GG	5,604,344	02-18-1997	Finarov et al.
N-B	GH	5,596,411	01-21-1997	Fanton et al.
N-B	GI	5,412,473	05-02-1995	Rosencwaig et al.
N-J	GJ	5,329,357	07-12-1994	Bernoux et al.

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	HA			
	HB			

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N-B	IA	BENESCH, NORBERT et al., "Phi-Scatterometry for Integrated Linewidth Control in DRAM Manufacturing," 2001 IEEE International Symposium on Semiconductor Manufacturing, October 8-10, 2001, pp. 129-132, IEEE Catalog No. 01CH37203, San Jose, California, USA.		
N-B	IB	COULOMBE, STEPHEN A. et al., "Scatterometry measurement of sub-0.1 μm linewidth gratings," Journal of Vacuum Science & Technology B: Microelectronics and Nanometer Structures, January, 1998, pp. 80-87, Vol. 16, Issue 1, American Vacuum Society, Research Triangle Park, North Carolina, USA.		

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Sheet	4	of	4	Attorney Docket Number	
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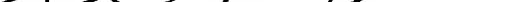
U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

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	KA			
	KB			

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

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N.B.	LA	RAYMOND, CHRISTOPHER J. et al., "Multiparameter grating metrology using optical scatterometry," Journal of Vacuum Science & Technology B: Microelectronics and Nanometer Structures, March, 1997, pp. 361-368, Vol. 15, Issue 2, American Vacuum Society, Research Triangle Park, North Carolina, USA.	
P.J.	LB	GIOVANNINI, H. et al., "Angle-resolved polarimetric phase measurement for the characterization of gratings," Optics Letters, October 15, 1996, pp. 1619-1621, Vol. 21, No. 20, Optical Society of America, Washington, DC, USA.	

Examiner Signature  **Date Considered** *1 Nov 2004*

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